



2880

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: Jaime Poris
Assignee: Nanometrics Incorporated
Title: Method Of Measuring Dishing
Serial No.: 09/578,798 Filing Date: May 23, 2000
Examiner: Unknown Group Art Unit: Unknown
Docket No.: M-8555 US

San Jose, California
February 5, 2001

COMMISSIONER FOR PATENTS
Washington, D. C. 20231

INFORMATION DISCLOSURE STATEMENT
UNDER 37 CFR § 1.97(b)

Dear Sir:

Pursuant to 37 C.F.R. § 1.56, § 1.97 and § 1.98, the documents listed on the accompanying PTO Form-1449 are called to the attention of the Examiner for the above patent application. Copies of these documents are enclosed.

Citation of these documents shall not be construed as:

1. an admission that the documents are necessarily prior art with respect to the instant invention;
2. a representation that a search has been made; or
3. an admission that the information cited herein is, or is considered to be, material to patentability as defined in § 1.56(b).

I hereby certify that this correspondence is being deposited with the United States Postal Service as First Class Mail in an envelope addressed to: Commissioner for Patents, Washington, D.C. 20231, on February 5, 2001.

Michael J. Halbert 2-5-01
Attorney for Applicant Date of Signature

Respectfully submitted,

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U.S. Department of Commerce, Patent and Trademark Office		Pat. Atty. Docket No.	Serial No.
		M-8555 US	09/578,798
INFORMATION DISCLOSURE STATEMENT BY APPLICANT		Applicant	
(Use several sheets if necessary)		Jaime Poris	
		Filing Date	Group
		May 23, 2000	Unknown 2873

U.S. Patent Documents

*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
W.C.	AA	5,784,163	7/21/98	Lu et al.	356	351	
W.C.	AB	5,872,629	2/16/99	Colvard	356	349	
W.C.	AC	5,874,318	2/23/99	Baker et al.	438	8	
W.C.	AD	5,953,115	9/14/99	Landers et al.	356	237	
W.C.	AE	5,983,167	11/9/99	Ebisawa	702	167	

Foreign Patent Documents

							Translation	
		Document	Date	Country	Class	Subclass	Yes	No
W.C.	AF	EP 0 982 774 A2	3/1/00	Europe				
W.C.	AG	WO 00/54325	9/14/00	PCT				

OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)

W.C.	AH	Azzam, R. et al., "Ellipsometry And Polarized Light" <i>Elsevier Science B.V.</i> (1977, 1987), Pages 282-287.
W.C.	AI	Fujiwara, H. et al., "Depth-profiles in compositionally-graded amorphous silicon alloy thin films analyzed by real time spectroscopic ellipsometry" <i>Elsevier Science S.A.</i> pages 474-478 (1998).
W.C.	AJ	Heavens, O. S., "Optical Properties of Thin Solid Films" <i>Dover Publications, Inc.</i> (1991), Pages 62-73.
W.C.	AK	Jennewin, H. et al., "Interferometrical Profilometry at Surfaces with Varying Materials" <i>SPIE Vol. 3677</i> (1999), Pages 1009-1016.
W.C.	AL	Kildemo, M. et al., "Measurement of the absorption edge of thick transparent substrates using the incoherent reflection model and spectroscopic UV - visible - near IR ellipsometry" <i>Elsevier Science S.A.</i> pages 108-113 (1998).
W.C.	AM	Kim, Gee-Hong et al., "White light scanning interferometry for thickness measurement of thin film layers" <i>SPI Vol. 3783</i> (1999), Pages 239-246.
W.C.	AN	Makosch, G. et al., "Surface profiling by electro-optical phase measurements" <i>SPIE Vol. 316</i> (1981); Pages 42-53.
W.C.	AO	"Numerical Recipes, The Art of Scientific Computing" by Press, Flannery, Teukolsky and Vetterling, published by Cambridge University Press 1988, 3.2 Rational Function Interpolation and Extrapolation, Pages 83-85.

Examiner

Date Considered

*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with your communication to applicant.